



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/625,166
Filing Date July 22, 2003
Confirmation No. 8008
Inventor Janos Fucsko et al.
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner Stephen W. Smoot
Attorney's Docket No. MI22-2246
Customer No. 021567
Title Wet Etching Method of Removing Silicon From a Substrate

RESPONSE TO DECEMBER 21, 2005 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

VIA U.S. EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)
Wells St. John P.S.
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Responsive to the Office Action dated December 21, 2005, Applicant
amends and remarks as follows:

AMENDMENTS